Multi-material glass AM and possibilities for TO of optical systems

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LLNL has invested heavily in advanced manufacturing of optics to enable future missions

Bulk compositional gradients



Laser rod with engineered gain profile (YAG) 10-cm core-clad rod First light

I. Jones *et al.*, *Opt. Mater.* 75: 19-25, 2018.

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Glass optic with gradient refractive index (GRIN)

1-cm GRIN lens Optical index homogeneity



Mirror and support with gradient stiffness 7-cm flat mirror Conventionally polishable





Metasurface optics with tunable reflectivity

2-cm durable AR meta-surfaces in glass by scalable process

J. Yoo *et al.,* ACS Appl. Mater. Interfaces 11, 22684-22691 (2019)

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Compositional gradients in glass are achieved using direct ink writing (DIW) of SiO₂ slurries with active mixing



Nguyen, D.T. et al., Adv. Mater. 2017, 29 (26), 1701181

Dudukovic, N. A. et al., ACS Applied Nano Mater. 2018, 1 (8), 4038-4044.





Using TiO₂-doped SiO₂ inks, we have produced flat GRIN glass optics with three different functionalities; max Δn of ~0.01



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Manuscript in preparation



DIW also enables material switching to yield regions of glass with distinct material properties

Printed low density form



Consolidated glass



Cross section of step-graded glass





Dry,

Radial step







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Topology optimization combined with AM can be used to impact performance of <u>individual</u> optical elements



TO = Topology Optimized



Topology optimization combined with AM can be used to impact performance of individual optical elements





GRIN = Gradient Index TO = Topology Optimized



Topology optimization can be used to impact performance of the optomechanical <u>system</u>



M. Langelaar, Delft University of TechnologyS. Koppen et al., Structural and Multidisciplinary Optimization (2018) 58:885–901



System level optomechanical system optimization can be further enhanced by <u>including meta materials and multiple materials</u>

- Optimal band gap materials serve as perfect reflectors
- Light weight supports enable fuel savings
- Mounts with thermally insensitive materials ensure accuracy



Perfect reflectivity mirror material





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Zero CTE mount material



Equal stiffness support with 50% weight savings



Challenges or barriers to implementation

- Integration of optical performance tools with TO tools
- Broadening the range of 3d printable materials
- More exploration of integration of disparate materials
- Scale-up still needed in a variety of materials/multi-material systems





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